



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of Invention	METHOD AND APPARATUS USING INTERFEROMETRIC METROLOGY FOR HIGH ASPECT RATIO INSPECTION						
Application Number: 10/672298							
Confirmation Number: 4459							
First Named Applicant: Shiow-Hwei Hwang							
Attorney Docket Number: KLA1P067/P995							
Art Unit: 2621							
Search string: (4818110 or 6262818 or 6078392).pn.							
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
PJL	1	4818110	1989-04-04	Davidson		356	358
PJL	2	6262818	2001-07-17	Cuche et al.		359	-9-
PJL	3	6078392	2000-06-20	Thomas et al.		356	-457
Signature							
Examiner Name				Date			
PATRICK CONNOLLY				11-PM 2005			